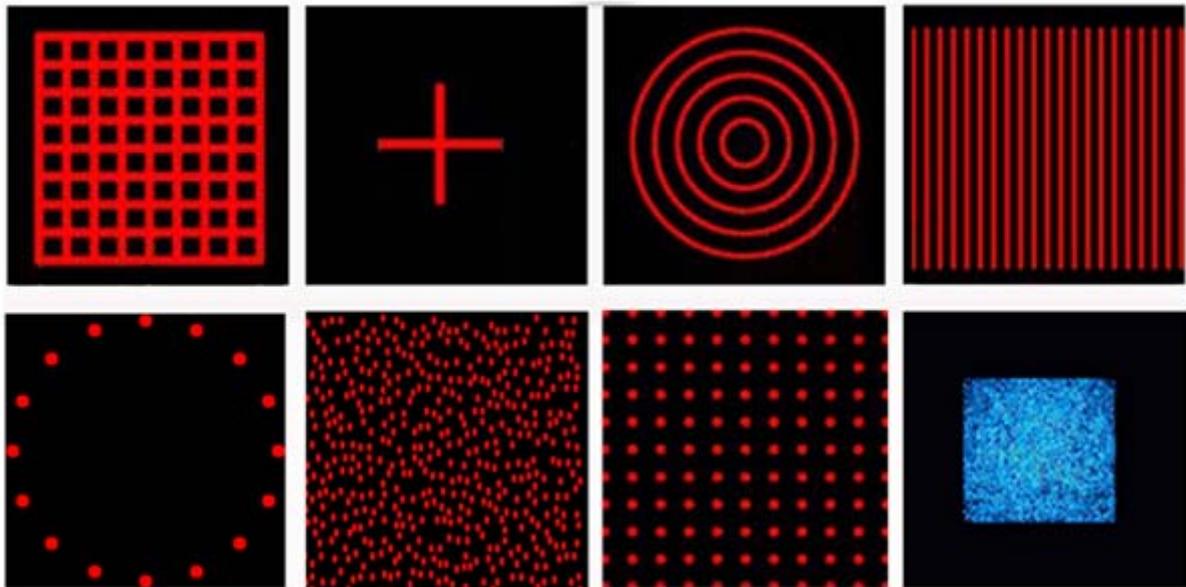


Micro- & Nano- Refractive & Diffractive Optics



无锡奥普顿光电子有限公司

Wuxi OptonTech Ltd



Wuxi OptonTech Ltd

Wuxi OptonTech Ltd. specializes in diffractive optical elements (DOEs) and computer generated holograms (CGHs) for beam shaping, beam splitting and beam homogenizing (dif fusing). We design and provide standard and custom DOEs and CGHs for high-performance laser and LED applications at competitive prices. We address the market needs high precision (virtually zero reconstruction error within the signal window) and high efficiency.

Web: <http://www.edphoton.com>

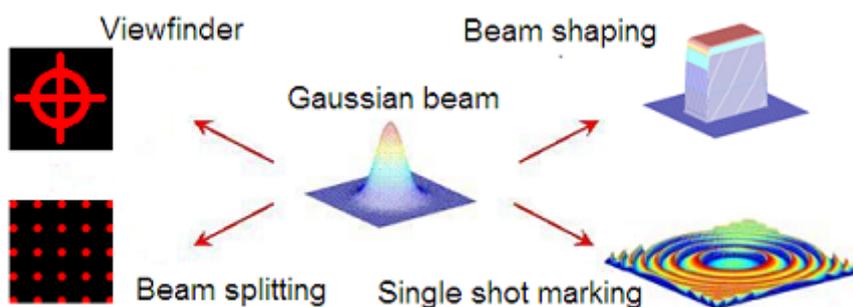
E-mail: sales@edphoton.com

Address: Room 1109, 16 Changjiang Road, Wuxi New

Tel: +86-510-81814590

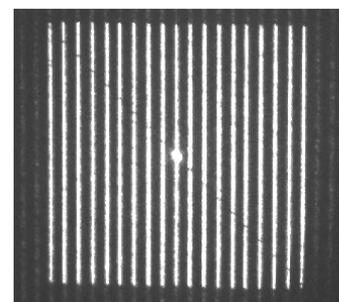
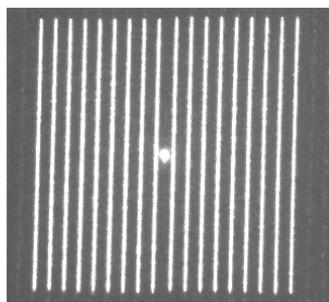
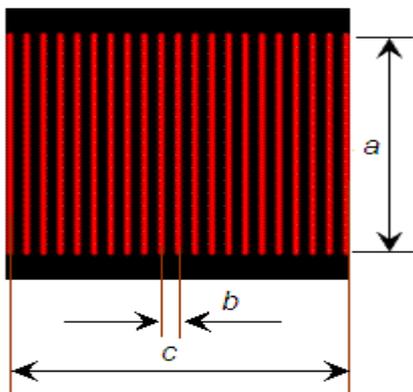
District (WND), Wuxi, Jiangsu Province, China

Fax: +86-510-81814590-603



DOEs can convert a Gaussian beam to a beam with almost any intensity distribution

Structured light: Multi-line/stripe



Multi-line images generated by our DOEs. Taken with a point--and shoot camera

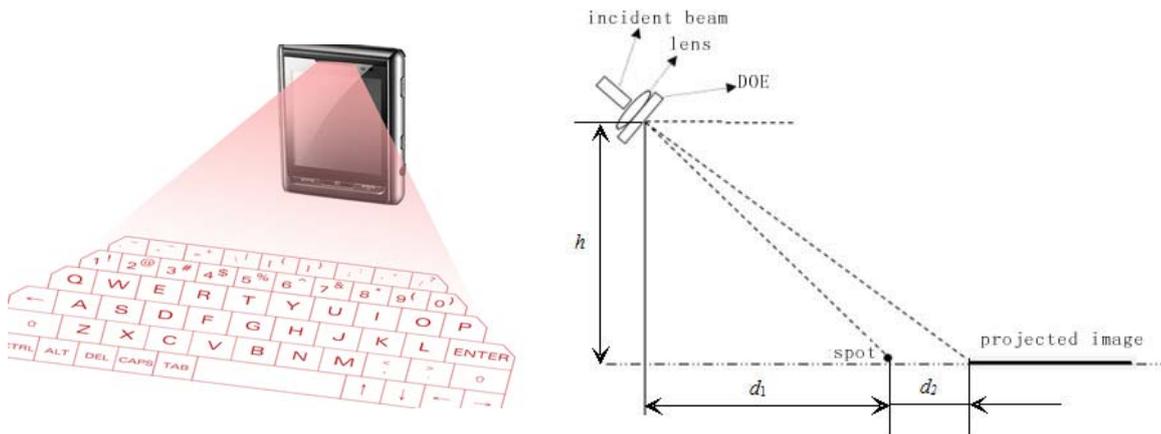
| Item No | Light receiving area | Separation angle at 650nm corresponding to a, b and c | Imagesizeat650 nm and working distance of 1000 mm | Remarks |
|---------|----------------------|--|--|----------|
| L1 | 6.5x 6.5 mm | $a = 4.91^\circ$ $b = 0.27^\circ$ $c = 4.62^\circ$ | $a = 86 \text{ mm}$ $c = 4.7 \text{ mm}$ $c = 81 \text{ mm}$ | 18 lines |
| L2 | 6.5 x 6.5 mm | $a = 4.5^\circ$ $b = 0.24^\circ$ $c = 4.34^\circ$ | $a = 78 \text{ mm}$ $b = 4 \text{ mm}$ $c = 76 \text{ mm}$ | 19 lines |

Laser virtual holographic keyboard

On July 31, 2012, Wuxi OptonTech Ltd fabricated the first DOE can be used for virtual holographic keyboard.

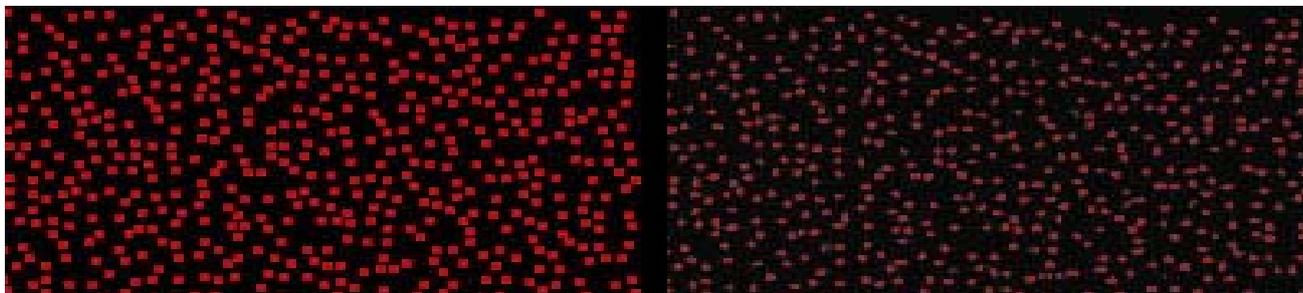
In a laser virtual holographic keyboard, it usually uses a red laser as the light source, and generates a virtual keyboard image on a plane by the DOE. It uses an infrared laser beam and CMOS sensors to detect the users' finger position.

To design a virtual holographic keyboard, we need you to provide the keyboard image and its dimensions. We also need to know the vertical distance h between the DOE and the projection plane, the horizontal distance (d_1+d_2) between the DOE and the top of the image, where d_2 is the distance between the the zero order and the top of the image.



Motion sensing and gesture recognition

For Infrared laser based human body motion sensing and gesture recognition systems, DOEs are without doubt an ideal solution. This is because DOEs can convert a laser beam to virtually arbitrary intensity distribution that matches the requirements of customers very well.



The upper left picture shows a customer's desired pattern, and the upper right is an actual pattern generated by our designed and fabricated DOE. It can be seen that the two patterns are in excellent agreement with each other.

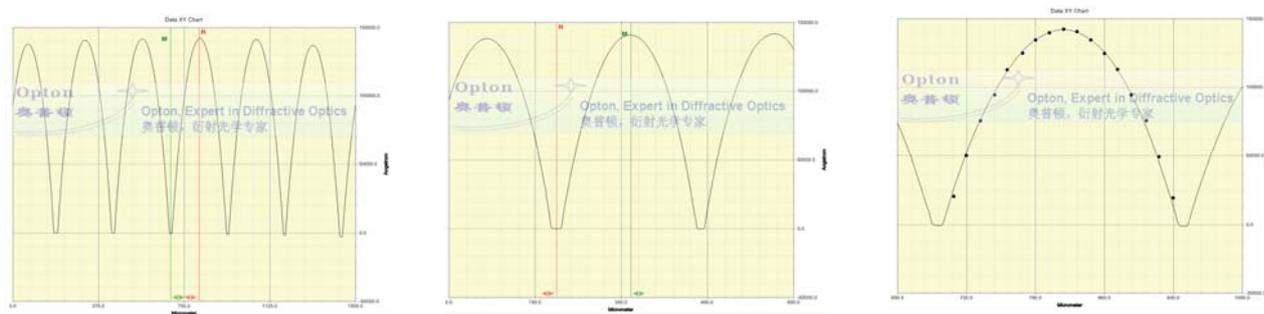
Left: Highly compatible, high-performance structured light by a DOE designed and fabricated by Wuxi OptonTech Ltd

Micro refractive and diffractive lens

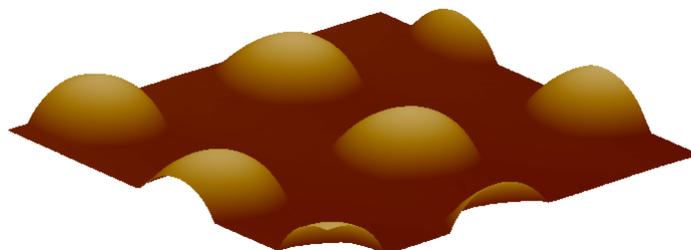
We provide both refractive microlens array and diffractive microlens array.



Illustration of refractive and diffractive microlens array



Surface profile of 250 micron microlens array. The scattered spots represent a perfect spherical profile. The non-symmetry is caused by the measurement error of the profilometer, which is ideal to measure the height differences but may have error during the measurement of continuous profiles. The radius of curvature at the vertex of the profile is 547 micron. The conic constant is approximate 0.5.

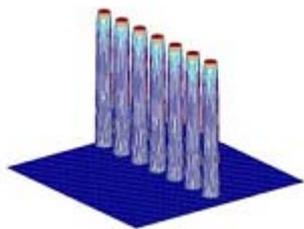


AFM picture of 140 micron microlens array. The non-symmetry is caused by the measurement error of AFM, which is ideal to measure the height differences but may have error during the measurement of continuous profiles

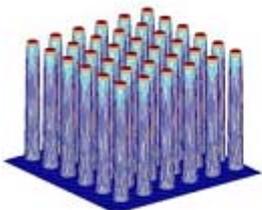
| Pitch | Microlenses Number | Element size | Radius curvature (um) | Focal length (um) |
|--------------|--------------------|--------------|-----------------------|-------------------|
| 7x7 um | 2800x2800 | 20x20 mm | ~3 | ~7 |
| 14x14 um | 570x570 | 8x8 mm | 7~15 | 12~36 |
| 150 x 150 um | 50x50 | 8x8 mm | 690 | ~1500 |
| 250 x 250 um | 32x32 | 8x8 mm | ~547 | ~1000 |

Beam splitter

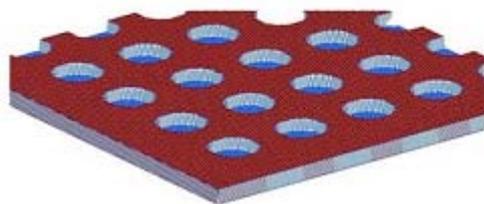
Beam splitters can be used for simultaneous laser drilling (perforating) of multi-holes, fiber coupling, etc. Specific applications of laser drilling include pre-weakening of cartons and metal-foils in packaging industry, high-speed laser texturing, cigarette filters, etc. We can split a single beam into up to a million highly uniform beams.



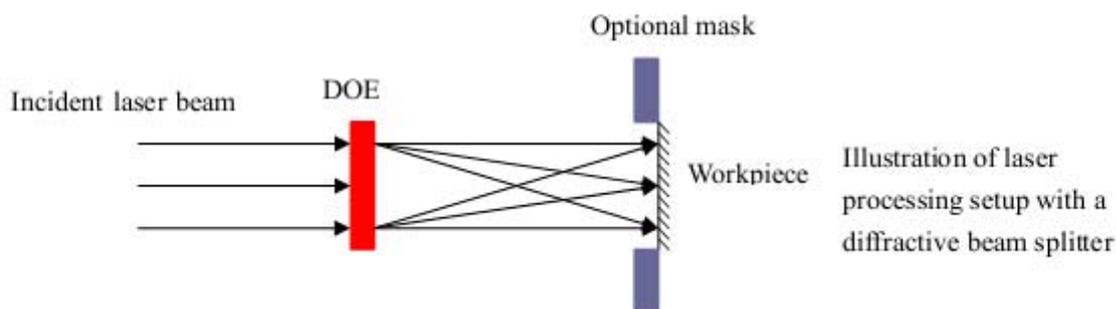
1-D Beam Splitting



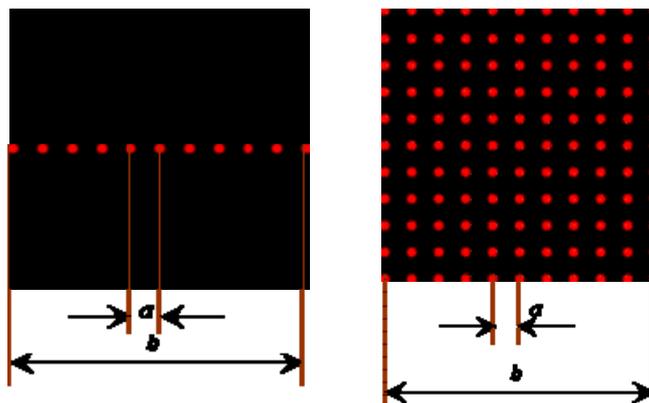
2-D Beam Splitting



Simultaneous laser drilling of multi-holes by 2-D beam splitters



Product nomination for diffractive beam splitter elements

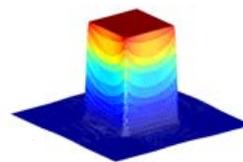
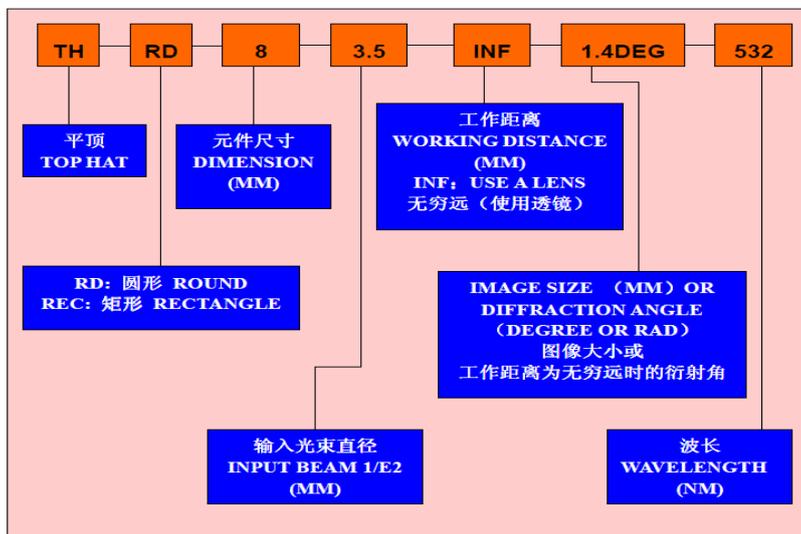


| Product Item | Light Receiving area | Number of Spots | Separation angle corresponding to a and b | Wavelength |
|--------------------------|----------------------|-----------------|---|--------------------------------------|
| BS-1D-8-1x3-40DEG-808 | 8 x 8 mm | 1x3 | A = 40° B = 80° | 808 nm (other wavelengths available) |
| BS-1D-8-1x24-0.17DEG- | 7.5 x 7.5mm | 1x24 | A = 0.17° B = 4.0° | 808 nm (other wavelengths available) |
| BS-1D-8-1x25-0.17DEG-808 | 7.5 x 7.5mm | 1x25 | A = 0.17° B = 4.2° | 808 nm (other wavelengths available) |
| BS-2D-8-10x10-532 | 8 x 8 mm | 10 x10 | A = 0.38° | 532 nm |

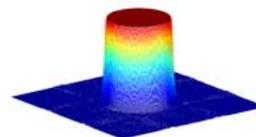
Top Hat Beam shaper

Diffractive beam shapers convert a laser beam with Gaussian intensity distribution into a beam with an accurate and almost arbitrary intensity distribution. Specific applications include precise control of treatment depth in laser heat treatment, laser hardening, cladding; turning a laser beam into a square or hexagon to increase the fill-factor in laser direct writing; and laser tweezers, etc.

Product nomination for diffractive top-hat beam-shaping elements



Gaussian to rectangular top-hat



Gaussian to circular top-hat

| Product Item | DOE size | Image size | wavelength | Working distance |
|------------------------------|----------|------------|------------|------------------|
| TH-RD-8-3-300-0.5-2080 | 8mm | 0.5mm | 2080nm | 300mm |
| TH-RD-8-3-300-1-2080 | 8mm | 1mm | 2080nm | 300mm |
| TH-RD-8-3-300-2-2080 | 8mm | 2mm | 2080nm | 300mm |
| TH-RD-8-3-300-3-2080 | 8mm | 3mm | 2080nm | 300mm |
| TH-REC-8-2-INF-20mrad-1064 | 8 mm | 20 mrad | 1064 nm | Infinite |
| TH-REC-8-2-200-4x4-1064 | 8 mm | 4x4 mm | 1064 nm | 200 mm |
| TH-REC-8-2.5-INF-20mrad-1064 | 8 mm | 20 mrad | 1064 nm | Infinite |
| TH-REC-8-2.5-200-4x4-1064 | 8 mm | 4x4 mm | 1064 nm | 200 mm |
| TH-REC-8-3-INF-20mrad-1064 | 8 mm | 20 mrad | 1064 nm | Infinite |
| TH-REC-8-3-200-4x4-1064 | 8 mm | 4x4 mm | 1064 nm | 200 mm |
| TH-REC-8-3.5-INF-20mrad-1064 | 8 mm | 20 mrad | 1064 nm | Infinite |
| TH-REC-8-3.5-200-4x4-1064 | 8 mm | 4x4 mm | 1064 nm | 200 mm |
| TH-REC-8-4-INF-20mrad-1064 | 8 mm | 20 mrad | 1064 nm | Infinite |
| TH-REC-8-4-200-4x4-1064 | 8 mm | 4x4 mm | 1064 nm | 200 mm |
| TH-REC-20-8-1700-5x5-1064 | 20 mm | 5x5 mm | 1064 nm | 1700 mm |
| TH-REC--8-3-200-4x4-532 | 8 mm | 4x4 mm | 532 nm | 200 mm |
| TH-RD-8-3.5-200-0.5-532 | 8 mm | 0.5mm | 532 nm | 200 mm |
| TH-REC-8-3.5-200-1x1-532 | 8 mm | 1x1 mm | 532 nm | 200 mm |
| TH-REC-8-3.5-200-4x4-532 | 8 mm | 4x4 mm | 532 nm | 200 mm |

Intra-Cavity beam shaper

Traditional laser resonators generate laser beams with a Gaussian distribution. By using an intra-cavity DOE, the resonator can extract more energy and generate a more uniform super-Gaussian beam, thus greatly improve the electrical-optical conversion efficiency.

Long / short focal depth DOE

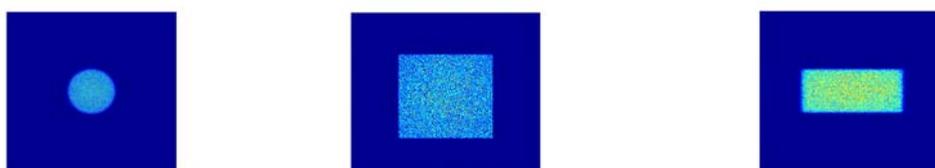
DOEs with long or short depth of focus can be achieved without changing the incident beam size or the working distance (focal length) as well as the focal spot size.

Beam sampler

Without affecting the main laser beam, a diffractive beam sampler produces two laser beams which are exactly the same as the main beam except for having lower power. These two low-power laser beam can be used for monitoring the intensity distribution of the main beam. We offer both reflective and transmissive beam samplers.

Beam homogenizer(Diffuser)

One main advantage of a beam homogenizer is its insensitivity to the incident beam quality and the change of intensity. Hence it is most suitable for the less stable lasers, laser with long pulse duration or multi-pulse laser applications. Due to the lengthy exposure time, the intensity fluctuation can be averaged to some extent. For a circularly symmetric output beam, the variation in intensity can be further impressed by rotating the beam homogenizer.



Output laser beam spots by diffusers

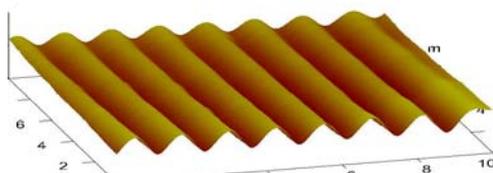
| Item No | DOE size | wavelength | Diffraction angle |
|---------------|----------|------------|-------------------|
| DF-RD-6-2-473 | 6 x 6 mm | 473 nm | 2° |
| DF-RD-6-3-589 | 6 x 6 mm | 589 nm | 3° |
| DF-RD-6-4-785 | 6 x 6 mm | 785 nm | 4° |
| DF-RD-6-4-808 | 6 x 6 mm | 808 nm | 4° |

Speckle free homogenizer

Recently Wuxi OptonTech Ltd is proud to introduce new diffractive optical elements (DOEs) which can produce speckle free homogenized output spots.

| Item No | DOE size | wavelength | Diffraction angle |
|----------------------------|----------|------------|-------------------|
| SFH-REC-12-p15xp45mrad-355 | 12x12 mm | 355 nm | 0.15x0.45 mrad |
| SFH-REC-25-p15xp45mrad-355 | 25x25 mm | 355 nm | 0.15x0.45 mrad |
| SFH-REC-18-4mrad-355 | 18x18 mm | 355 nm | 4 mrad |
| SFH-REC-18-5p2mrad-355 | 18x18 mm | 355 nm | 5.2 mrad |

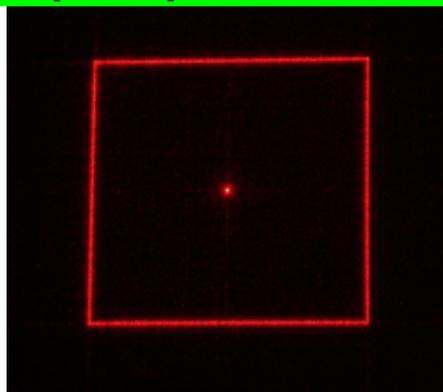
Phase gratings for optical linear encoder



AFM image of our fabricated DOE.
Size:10x10micron.

Grating ruler general use infrared LED, visible light LED, and small light bulbs or semiconductor laser as light source, using moore provisions, diffraction or holographic principle to high precision position measurement, mainly used in modern machine tools, machining centers and various measuring instruments. Grating ruler can be used for linear displacement or angular displacement measurement, the accuracy is commonly from hundreds of microns to submicron, through interpolation, the resolution can reach one nanometer.

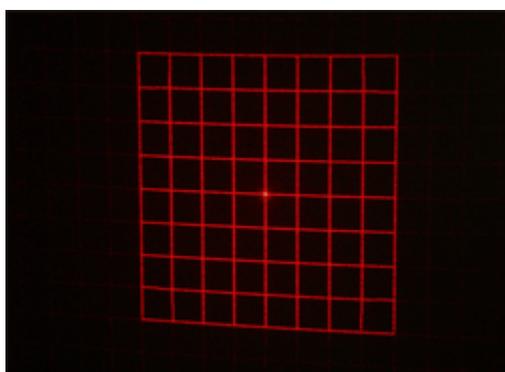
Square pattern



Zero order: ~3% of incident laser power
Intensity of ghost image: ~5% of the signal intensity

The left picture shows the image of the actual square pattern produced by our designed and fabricated DOE. The image was taken with a point-and shoot camera.

Grids



Full angle: 5.8 degrees at 650 nm
Zero order: ~2% of incident laser power
Intensity of ghost image: ~5% of the signal intensity

The left picture shows the image of the actual square pattern produced by our designed and fabricated DOE. The image was taken with a point-and shoot camera.

| Item No | DOE size | Full angle at 650 nm | Description |
|---------|----------|----------------------|-------------|
| G8-8 | 6x6 mm | 8 deg | 8x8 grids |
| G9-8 | 6x6 mm | 8 deg | 9x9 grids |

Rings



| Item No | DOE size | Image size at 650 nm & 1000 mm distance | Description |
|---------|----------|--|-----------------------|
| R9-1 | 8x8 mm | $r_1=9.7 \text{ mm}$ $r_9=87.5 \text{ mm}$ | 9 evenly-spaced rings |
| R5-1 | 6x6 mm | $r_1=11.90 \text{ mm}$ $r_2=23.80 \text{ mm}$ $r_3=35.71 \text{ mm}$ $r_4=47.61 \text{ mm}$ $r_5=59.51 \text{ mm}$ | 5 evenly-spaced rings |

Crosshair



| Item No | DOE size | Diffraction angle at 532 nm |
|----------------|----------|-----------------------------|
| CH-2014-2-24-1 | 5 x 5 mm | 20 deg |
| CH-2014-2-24-2 | 5 x 5 mm | 60 deg |

Taken with a point-and shoot camera

We need the following parameters to provide you custom DOEs

DOEs you would like to order:

- Beam splitter; Top-hat beam shaper; Other beam shaping; microlens array;
 inclined surface beam shaping (virtual holographic keyboard); Other applications

Required diffractive efficiency: _____

Please attach your required target image (irradiance/intensity distribution) if necessary

Wavelength: _____

Material: _____

Dimensions and shape of DOE: _____

Incident beam diameter(radius x 2): _____

The input laser power and laser type: _____

Mode (Single Mode or Multi Mode): _____

(beam splitting) Separation angle of 2 adjacent output beams: _____

(Tot-hat) working distance: _____

Size of output beam spot or diffraction angle of output beam: _____

(Laser oblique projection) Output image and the size: _____

The vertical distance diffraction element to the projection plane h , Diffraction element to the image at the top of the horizontal distance (d_1+d_2) ,

And the projection plane of zero level to the top of the image distance d_2 : _____

(microlens array) Pitch between microlens: _____

Micro lens focal length: _____

Overall size device (LWH): _____

If plating coating: _____

Specifications

Material: Fused silica, BK7 (K9) glass, resin, PC, GaAS etc.

Wavelength: 193-10600 nm

Dimension,,: up to Φ 150 mm

Phase levels: 16

Feature size: >300 nm



Contact us

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